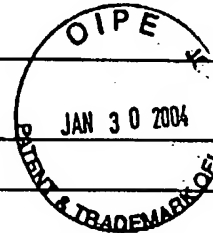


INFORMATION DISCLOSURE CITATION

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Applicant		Oscar David LABRAÑA VALDIVIA et al.	
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Examiner Initial*	Document Number	Issue Date	Name	Class	Sub Class	Filing Date If Appropriate
	5,204,082	04/20/1993	Schendel			
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)	
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Examiner		Date Considered	7.8.2004
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